Response under 37 C.F.R. § 1.116 **Expedited Procedure Examining Group 1763**

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket No: NOVEP015 In re application of: Group Art Unit: 1763 Robert A. SHEPHERD JR et al. Examiner: Zervigon, Rudy Application No: 10/006,100 10 Filed: December 3, 2001

Date: October 27, 2003

METHOD AND APPARATUS For: FOR PLASMA OPTIMIZATION IN WAFER PROCESSING

Entered w. 17/31/03 RH 12/31/03

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Mail Stop AF, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on October 27, 2003.

Signed:

Feb Cabrasawan

RESPONSE TO FINAL OFFICE ACTION

Mai Stop AF 30 Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

This Amendment is in response to a FINAL Office Action dated August 27, 2003. 35

Please enter the following remarks.

Remarks begin on page 2.

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